Search Notes

Application/Control No.	Applicant(s)/Patent under Reexamination	
10/705,884	SHIRAISHI ET AL.	
Examiner	Art Unit	
Paul D. Kim	3729	

SEARCHED					
Class	Subclass	Date	Examiner		
29	25.35 603.04 603.06 603.07	8/19/2005	PK		
156	64 307.1 379				
360	294.4 294.6	<b>√</b>			

INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
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	2.00				

SEARCH NO (INCLUDING SEARCH		)
	DATE	EXMR
Reviewed Parent Application 09/933,774 (US PAT. 6,690,551)	8/19/2005	PK
Text Search EAST/NPL (IEEE)	8/19/2005	PK
Updated Text Search EAST	11/2/2005	PK